·····	Application No.	Applicant(s)	
Notice of Allowability	10/676,877 Examiner	NODA, TAIJI Art Unit	
	Examiner	Artonic	
	Michael Trinh	2822	
The MAILING DATE of this communication apple All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate communication is supplication is supplication.	n this application. If not included unication will be mailed in due course.	THIS initiative
1. X This communication is responsive to RCE & Amendement	filed July 27, 2006.		
2. \boxtimes The allowed claim(s) is/are <u>1-5,7-14 and 18-37</u> .			
3. ☑ Acknowledgment is made of a claim for foreign priority un a) ☑ All b) ☐ Some* c) ☐ None of the:		or (f).	
1. Certified copies of the priority documents have		No	
2. Certified copies of the priority documents have			
3. Copies of the certified copies of the priority do	cuments have been receive	d in this national stage application from	the
International Bureau (PCT Rule 17.2(a)).			
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file IENT of this application.	a reply complying with the requiremer	ıts
 A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give 	itted. Note the attached EXA es reason(s) why the oath o	AMINER'S AMENDMENT or NOTICE Or declaration is deficient.)F
5. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.		
(a) including changes required by the Notice of Draftspers		v (PTO-948) attached	
1) hereto or 2) to Paper No./Mail Date		,	
(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date		in the Office action of	
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in t	.84(c)) should be written on the header according to 37 CF	ne drawings in the front (not the back) of R 1.121(d).	
 DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT 	sit of BIOLOGICAL MATI FOR THE DEPOSIT OF BIO	ERIAL must be submitted. Note the DLOGICAL MATERIAL.	
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. ☐ Notice of In	formal Patent Application (PTO-152)	
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview S	ımmary (PTO-413),	•
 Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 		Mail Date Amendment/Comment	
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. 🛭 Examiner's	Statement of Reasons for Allowance	
	9. 🗌 Other	Quel list	
		Michael Trinh	

Art Unit: 2822

DETAILED ACTION

*** This office action is in response to Applicant's RCE and Amendment filed July 27, 2006. Claims 1-5,7-14,18-37 are pending, in which claims 19-37 have been newly added.

Allowable Subject Matter

- 1. Claims 1-5,7-14,18-37 are allowed.
- 2. The following is a statement of reasons for the indication of allowable subject matter:

As already of record, Applicant's amendments and convincing remarks of record have overcome the rejections in the last office action. The references of record including Lee (2001/0041432), Sundaresan (6,190,179), Sonoda (6,696,341), etc., alone or in combination, do not fairly anticipatively disclose each and every aspect of the claimed method, or fairly make a prima facie obvious case of the claimed method as recited in base claim 1, the inclusion of a first step of implanting indium ions into the semiconductor substrate to form a dopant implantation layer in the channel formation region; a second step of implanting second dopant ions to form a first amorphous layer; after the first and second steps, performing a first thermal treatment to diffuse the first dopant ions from the dopant implantation layer, thereby forming a first diffused layer of the first conductivity type in the channel region; and after the third step, selectively forming a gate insulating film on the semiconductor substrate and a gate electrode thereon, wherein the first amorphous layer expands from the substrate surface to a region of the substrate deeper than the dopant implantation layer.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Michael M. Trinh whose telephone number is (571) 272-1847. The examiner can normally be reached on M-F: 9:00 Am to 5:30 Pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The central fax phone number is (703) 872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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Michael Trimi Primary Examinar